

**Search Notes**

Application No.

10/090,149

Examiner

H.Jey Tsai

Applicant(s)

AKUTSU ET AL.

Art Unit

2812

**SEARCHED**

Class	Subclass	Date	Examiner
355	53-76	3/28/2004	J
310	12-13	3/28/2004	J

**INTERFERENCE SEARCHED**

Class	Subclass	Date	Examiner
355	75	3/28/2004	J

**SEARCH NOTES  
(INCLUDING SEARCH STRATEGY)**

	DATE	EXMR

L Number	Hits	Search Text	DB	Time stamp
1	489213	alignment	USPAT; US-PGPUB	2004/03/26 10:39
2	2908258	system apparatus	USPAT; US-PGPUB	2004/03/26 10:39
3	48254	alignment near10 (system apparatus)	USPAT; US-PGPUB	2004/03/26 10:41
4	2238624	proces\$3	USPAT; US-PGPUB	2004/03/26 10:41
5	529123	proces\$3 near10 (system apparatus)	USPAT; US-PGPUB	2004/03/26 10:42
6	14356	((alignment near10 (system apparatus)) and (proces\$3 near10 (system apparatus)))	USPAT; US-PGPUB	2004/03/26 10:43
7	1366947	measur\$6	USPAT; US-PGPUB	2004/03/26 10:43
8	2134607	position	USPAT; US-PGPUB	2004/03/26 10:43
9	2458777	position location	USPAT; US-PGPUB	2004/03/26 10:44
10	142632	measur\$6 near10 (position location)	USPAT; US-PGPUB	2004/03/26 10:45
11	3960	((alignment near10 (system apparatus)) and (proces\$3 near10 (system apparatus))) and (measur\$6 near10 (position location))	USPAT; US-PGPUB	2004/03/26 10:45
12	659360	substrate wafer	USPAT; US-PGPUB	2004/03/26 10:50
13	968442	chuck stage holder	USPAT; US-PGPUB	2004/03/26 10:50
14	48609	(substrate wafer) near10 (chuck stage holder)	USPAT; US-PGPUB	2004/03/26 10:47
15	1424	((alignment near10 (system apparatus)) and (proces\$3 near10 (system apparatus))) and (measur\$6 near10 (position location)) and ((substrate wafer) near10 (chuck stage holder))	USPAT; US-PGPUB	2004/03/26 10:47
16	390607	chucks stages holders	USPAT; US-PGPUB	2004/03/26 10:50
17	283078	substrates wafers	USPAT; US-PGPUB	2004/03/26 10:50
18	3597	(chucks stages holders) with (substrates wafers)	USPAT; US-PGPUB	2004/03/26 10:51
19	103	((alignment near10 (system apparatus)) and (proces\$3 near10 (system apparatus))) and (measur\$6 near10 (position location)) and ((substrate wafer) near10 (chuck stage holder)) and ((chucks stages holders) with (substrates wafers))	USPAT; US-PGPUB	2004/03/26 10:52
20	1347508	light beam	USPAT; US-PGPUB	2004/03/26 10:52
21	103	((alignment near10 (system apparatus)) and (proces\$3 near10 (system apparatus))) and (measur\$6 near10 (position location)) and ((substrate wafer) near10 (chuck stage holder)) and ((chucks stages holders) with (substrates wafers)) and (light beam)	USPAT; US-PGPUB	2004/03/26 10:54
22	840334	plane	USPAT; US-PGPUB	2004/03/26 10:54
23	85	((alignment near10 (system apparatus)) and (proces\$3 near10 (system apparatus))) and (measur\$6 near10 (position location)) and ((substrate wafer) near10 (chuck stage holder)) and ((chucks stages holders) with (substrates wafers)) and (light beam) and plane	USPAT; US-PGPUB	2004/03/26 10:55
24	207246	proces\$3 with (substrate wafer)	USPAT; US-PGPUB	2004/03/26 10:56
25	81	((alignment near10 (system apparatus)) and (proces\$3 near10 (system apparatus))) and (measur\$6 near10 (position location)) and ((substrate wafer) near10 (chuck stage holder)) and ((chucks stages holders) with (substrates wafers)) and (light beam) and plane) and (proces\$3 with (substrate wafer))	USPAT; US-PGPUB	2004/03/26 10:57

26	64	(((((((alignment near10 (system apparatus)) and (proces\$3 near10 (system apparatus))) and (measur\$6 near10 (position location))) and ((substrate wafer) near10 (chuck stage holder))) and ((chucks stages holders) with (substrates wafers))) and (light beam)) and plane) and (proces\$3 with (substrate wafer))) and @ad<20020305	USPAT; US-PGPUB	2004/03/26 10:57
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